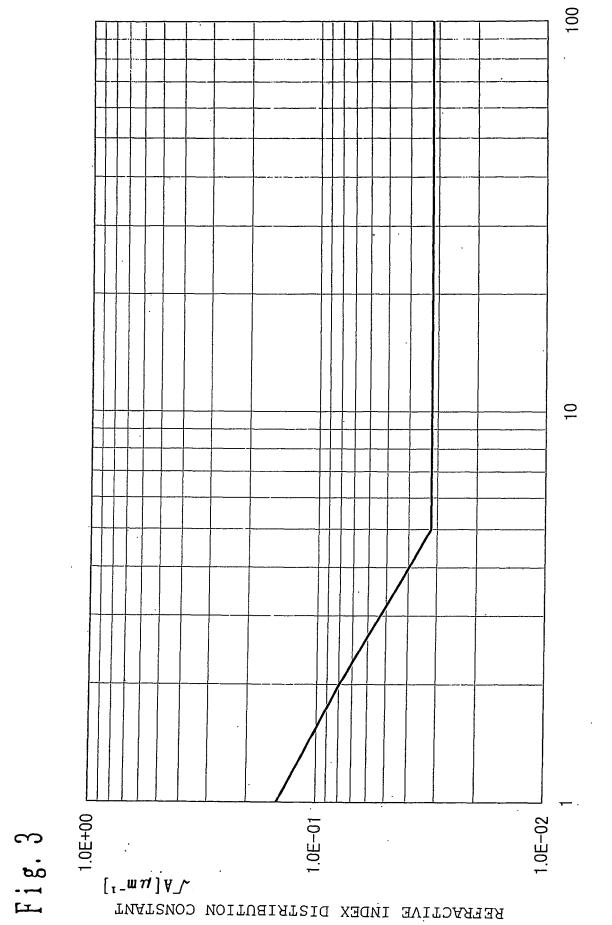
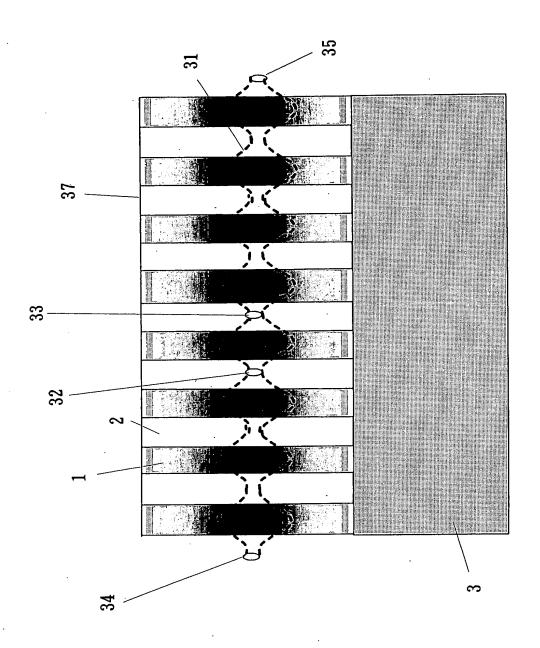
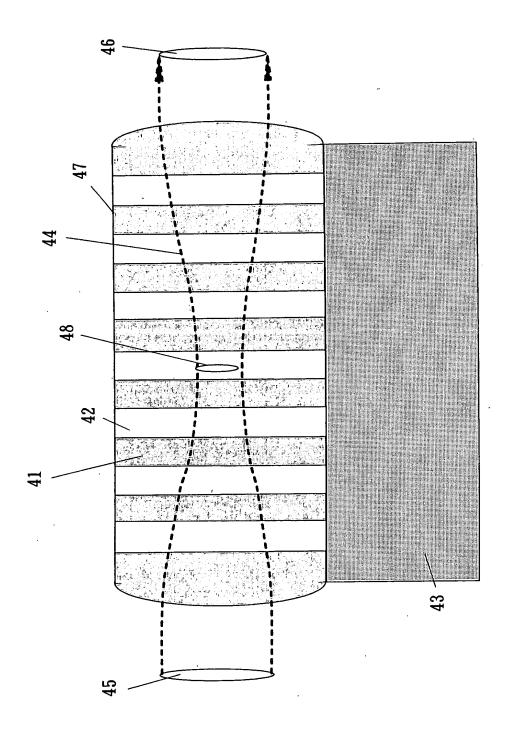
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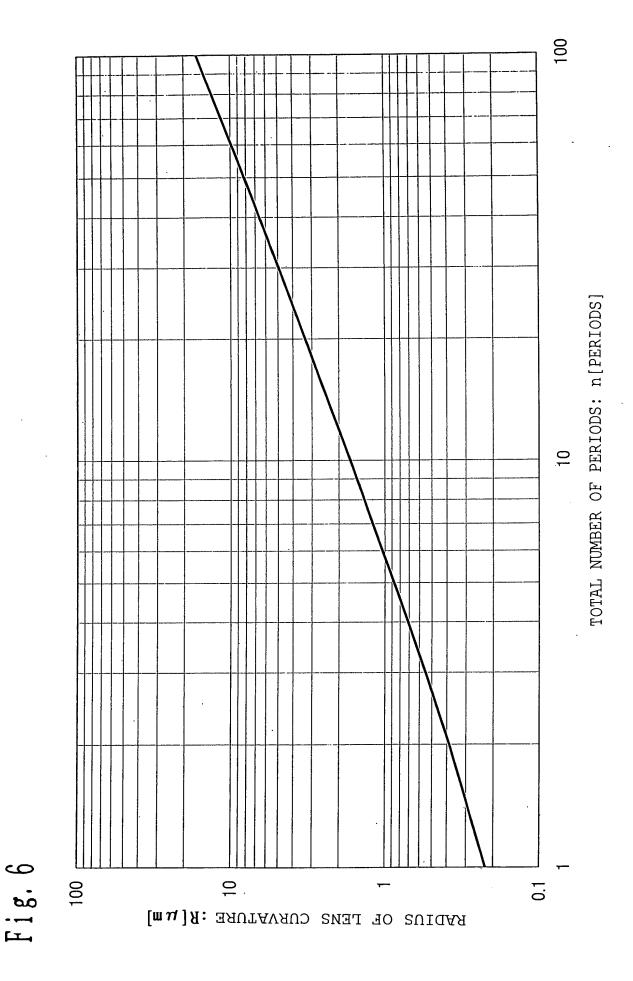


TOTAL NUMBER OF PERIODS n[PERIODS]





F1.09



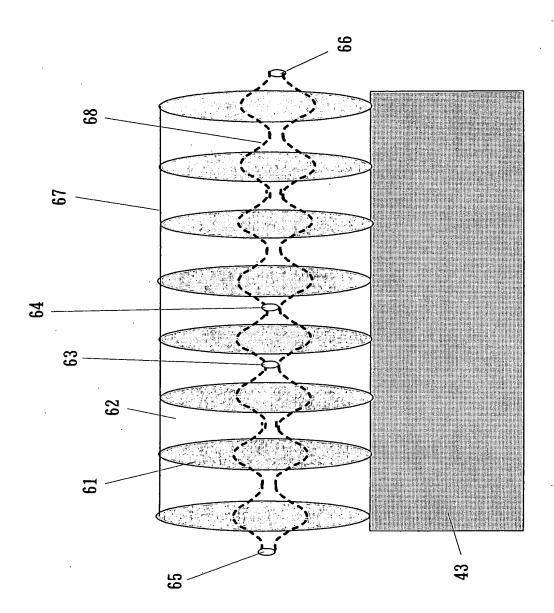
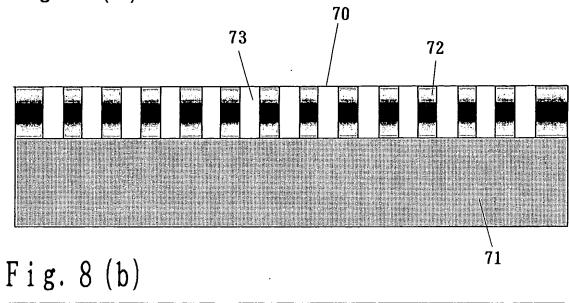


Fig. 8 (a)



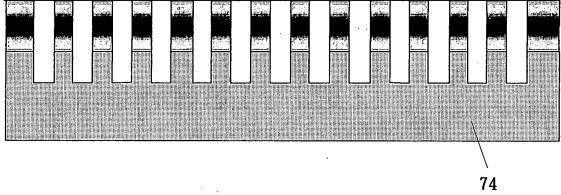
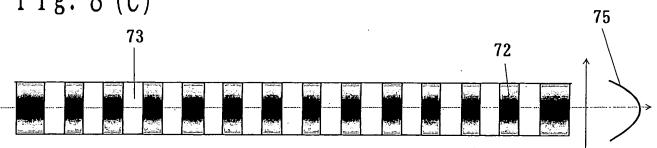
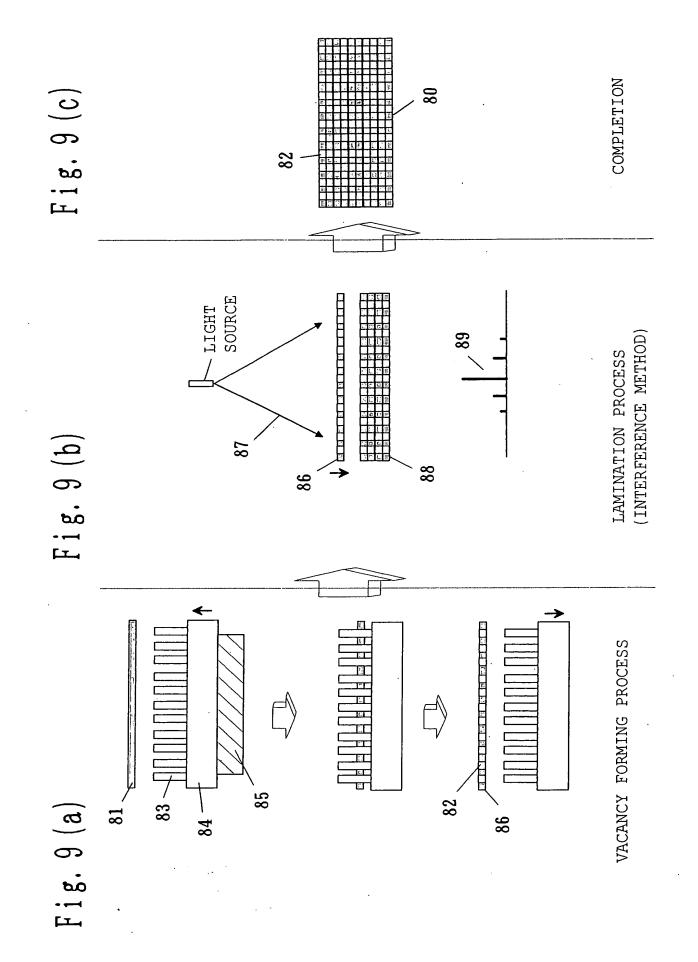


Fig. 8 (c)





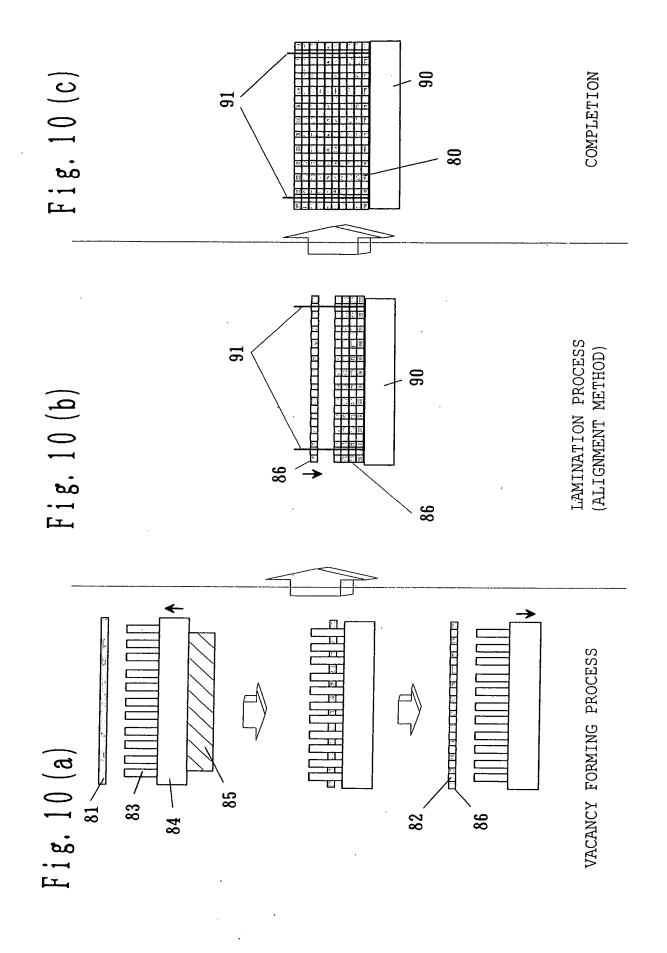
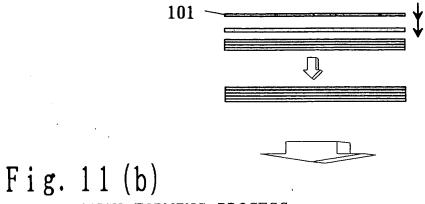
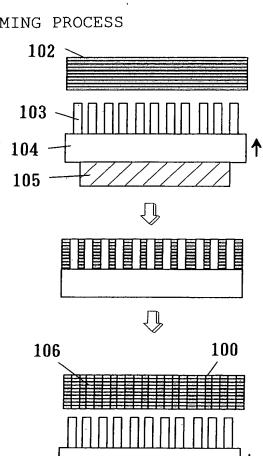


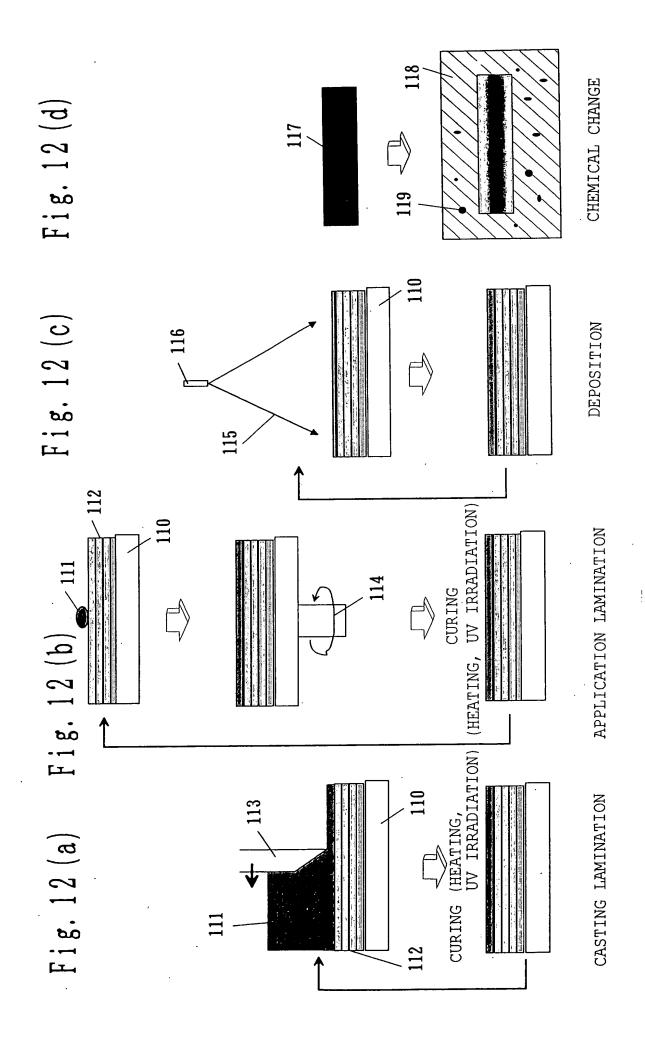
Fig. 11 (a)

REFRACTIVE INDEX DISTRIBUTED FILM MAKING PROCESS



VACANCY FORMING PROCESS





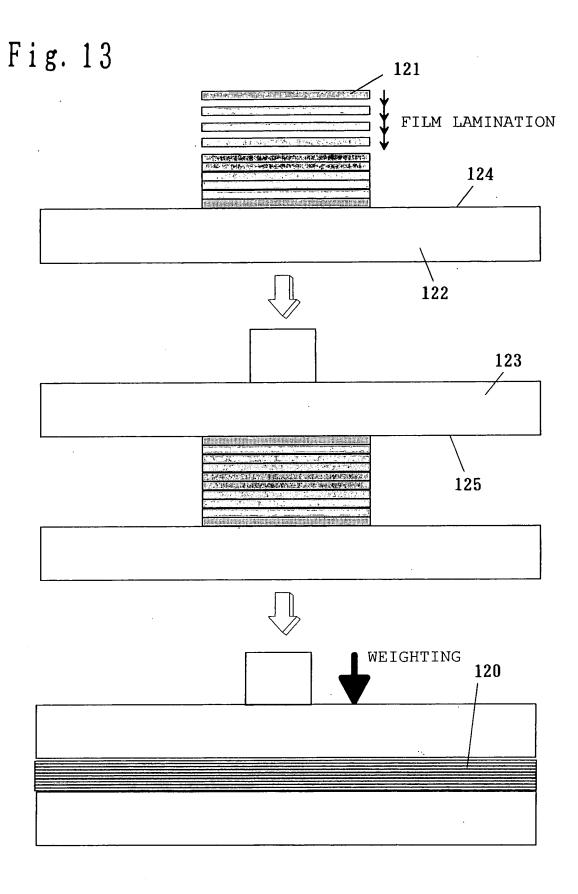
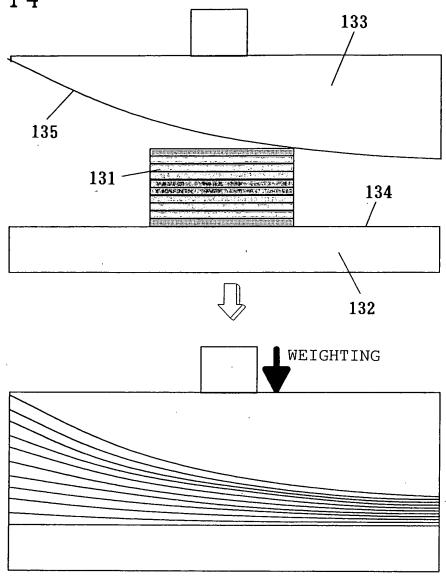


Fig. 14



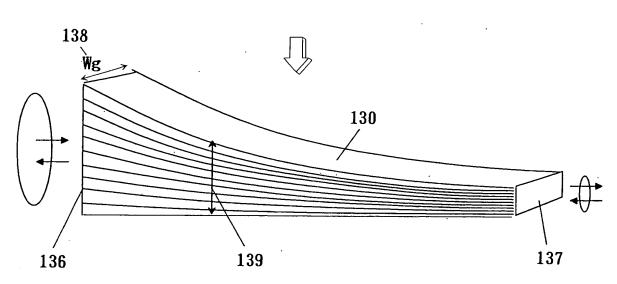
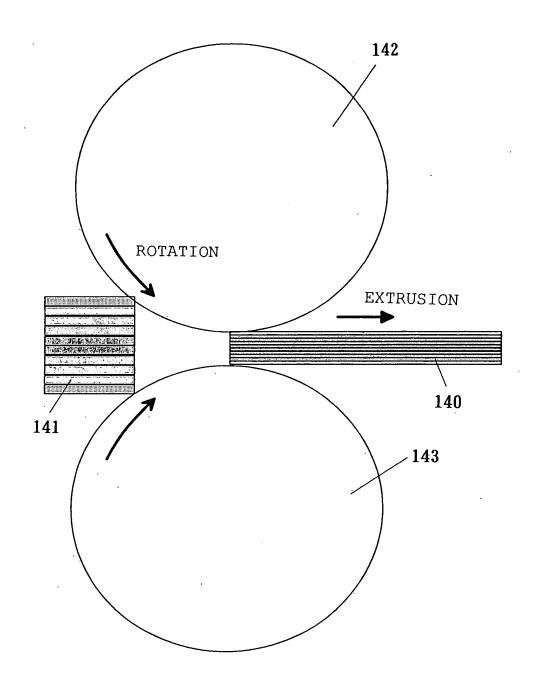
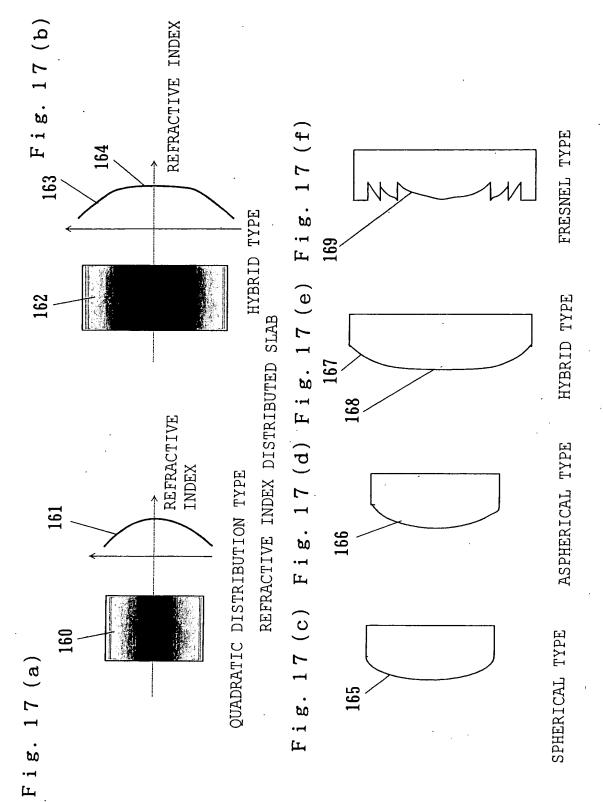


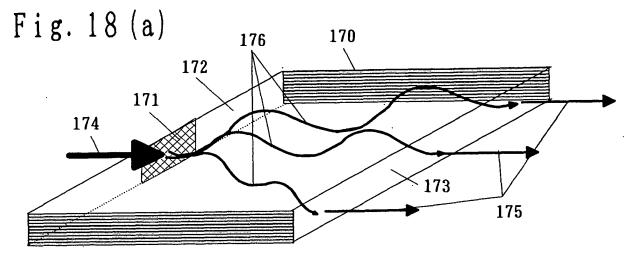
Fig. 15



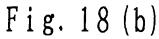
3 I G

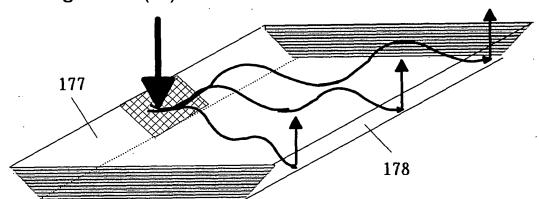


END SURFACE WORKED SLAB

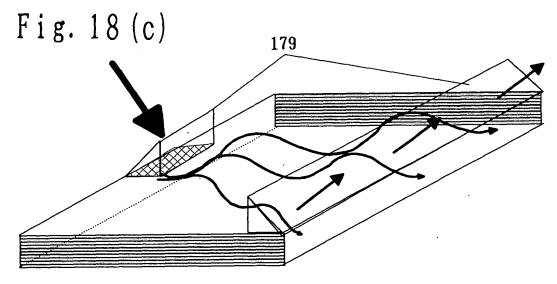


LINEAR-TYPE MULTICAST

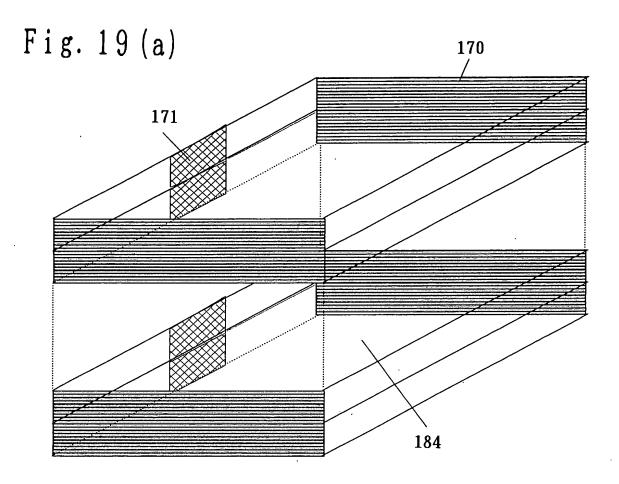




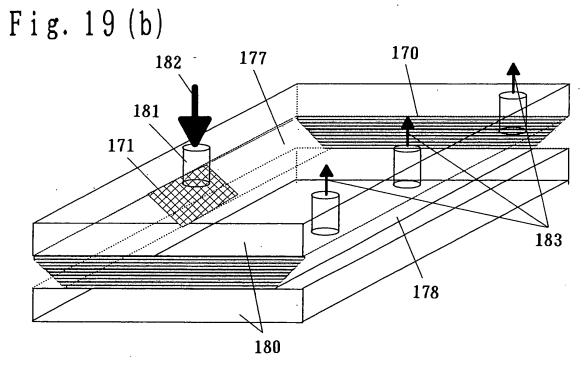
REFLECTION-TYPE MULTICAST



COUPLER-TYPE MULTICAST

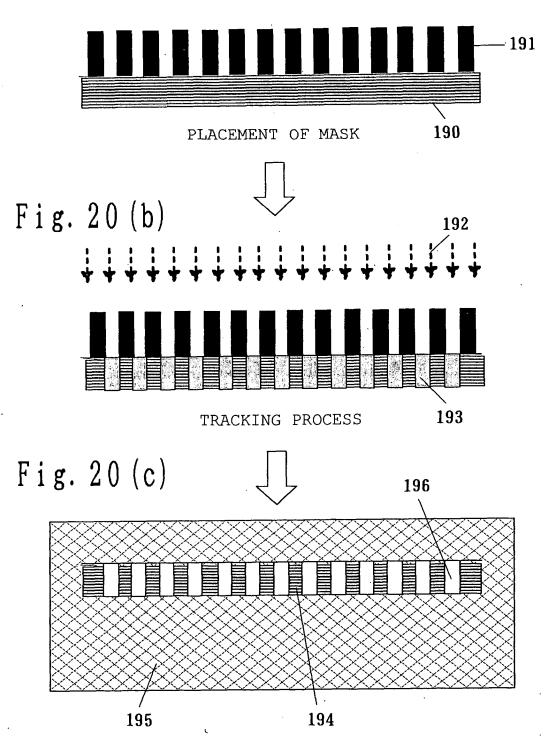


MULTILAYER SLAB WAVEGUIDE



HYBRID WAVEGUIDE

Fig. 20 (a)



ETCHING PROCESS

